

LOAD LOCK ARRANGEMENT COMPRISING A MICROWAVE HEATER FOR DESORBING MOISTURE AND SUBSTRATE PROCESSING APPARATUS

ABSTRACT

This disclosure relates to a load lock arrangement and a substrate processing apparatus comprising the load lock arrangement. The load lock arrangement comprises a load lock chamber body that defines a load lock chamber, a substrate holder for holding one or more substrates in the load lock chamber, and a microwave heater for desorbing adsorbed moisture from the one or more substrates.

Fig. 1